

## CLAIMS

1 1. A method of detecting binding to or reaction with a selective material, the method  
2 comprising the steps of:

3 a. providing a sensor comprising:

4 i. a diaphragm comprising a conductive portion;

5 ii. a selective coating on a first face of the diaphragm; and

6 iii. a counterelectrode spaced from and in opposition to the  
7 diaphragm, interaction of the selective coating with an analyte deforming the  
8 diaphragm and thereby altering a capacitance of the sensor; and

9 b. measuring a capacitance of the sensor to determine a degree of  
10 interaction between the analyte and the selective coating.  
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1 2. The method of claim 1 wherein the entire diaphragm is conductive.  
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1 3. The method of claim 1 wherein the diaphragm is compositionally uniform.  
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1 4. The method of claim 1 wherein the measurement step comprises comparing the  
2 sensor capacitance to a reference capacitance.  
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1 5. The method of claim 4 wherein the reference capacitance is equal to a  
2 capacitance of the sensor in the absence of interaction with the selective coating.  
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1 6. The method of claim 1 wherein the selective coating comprises a polypeptide.  
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1 7. The method of claim 6 wherein the selective coating comprises an antibody.  
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1 8. The method of claim 1 wherein the selective coating comprises an antigen.  
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1 9. The method of claim 1 further comprising the step of exposing at least the  
2 selective coating to a fluid, the measurement step indicating whether an analyte that  
3 binds to the coating is present in the fluid.

1 10. The method of claim 9 wherein the fluid comprises a gas.

1 11. The method of claim 9 wherein the fluid comprises a liquid.

1 12. The method of claim 1 wherein the deformation is proportional to a binding  
2 energy, which indicates a degree of binding.

1 13. A sensor comprising:

- 2 a. a diaphragm comprising a conductive portion;
  - 3 b. a selective coating on a first face of the diaphragm; and
  - 4 c. a counterelectrode spaced from and in opposition to the diaphragm,
- 5 interaction of the selective coating with an analyte deforming the diaphragm and  
6 thereby altering a capacitance of the sensor so as to indicate a degree of interaction.

1 14. The sensor of claim 13 wherein the entire diaphragm is conductive.

1 15. The sensor of claim 13 wherein the diaphragm is compositionally uniform.

1 16. The sensor of claim 13 wherein the selective coating covers only a portion of the  
2 first face of the diaphragm.

1 17. The sensor of claim 13 further comprising means for equalizing a pressure on  
2 each face of the diaphragm.

1 18. The sensor of claim 17 wherein the pressure-equalizing means comprises  
2 perforations through the counterelectrode.

1 19. The sensor of claim 13 wherein the coating covers a central half of the first face  
2 of the diaphragm.

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1 20. The sensor of claim 13 further comprising circuitry for reporting presence of the  
2 analyte.

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1 21. The sensor of claim 13 further comprising circuitry for reporting a concentration  
2 of the analyte.

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